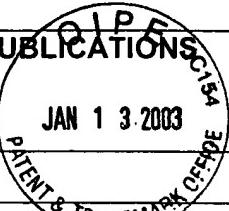


U.S. Department of Commerce, Patent and Trademark Office (PTO Form 1449 modified)		Docket No. APPM/5619	Serial No. 09/912,103
SUPPLEMENTAL LIST OF PATENTS AND PUBLICATIONS CITED BY APPLICANT		Applicant Nguyen, et al.	Confirmation No.: 4476
(Use several sheets if necessary)		Filing Date 07/23/2001	Group 2823
	Examiner K. Nguyen		

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*Examiner Initial		Document Number	Issue Date	Applicant(s) Name	Class	Subclass	Filing Date If Appropriate
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KN	A3	6,277,763	08/21/2001	Kugimiyama, et al.	438	720	12/16/1999
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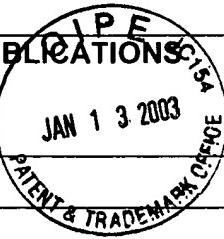
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Foreign Patent Documents

*Examiner Initial		Document Number	Date	Country	Class	Subclass	Translation	
							YES	NO
KN	B1	27 01 458 A1	07/21/1977	DE	G03C	5/48	<input type="checkbox"/>	<input checked="" type="checkbox"/>
KN	B2	0 552 491 A1	07/28/1993	EP	H01J	37/32	<input type="checkbox"/>	<input type="checkbox"/>
KN	B3	0 489 407 A2	06/10/1992	EP	H01J	37/32	<input type="checkbox"/>	<input type="checkbox"/>
KN	B4	09-082,686	03/28/1997	JP	H01L	21/3065	<input checked="" type="checkbox"/>	<input type="checkbox"/>
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	B 24						<input checked="" type="checkbox"/>	<input type="checkbox"/>

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OTHER ART

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KN	C3	Theisen, et al., "Maskless Tungsten Etch Process for Plug Fill", <i>1046b Extended Abstracts</i> , Electrochem Soc., Spring Meeting, 90(1) (May 6-11, 1990), pp. 248-249
KN	C4	Ootera, et al., "Highly Selective Etching of W/WN/Poly-Si Gate on Thin Oxide Film With Gaspuff Plasmas", Proc. of Symp.on Dry Process (Nov. 11-12,1999), pp. 155-160
KIN	C5	Hayashi, et al., SiO ₂ Etching Using Inductively Coupled Plasma", <i>Electronics & Communications in Japan</i> , Part 2, 81(9) (1998), pp. 21-28
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	C11	
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	C13	
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